近接昇華法による AgGaTe2 成長中 Ag2Te 層表面形態変化の分析

The surface morphology change analysis of Ag₂Te layers in the two-step closed space

sublimation process of AgGaTe₂

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AgGaTe₂ is a promising photovoltaic material available for using in high-efficiency solar cells. The growth of crystallized AgGaTe₂ thin films by the two-step closed space sublimation (CSS) method has been successfully demonstrated [1]. For the two-step CSS of AgGaTe₂ thin films, an Ag₂Te buffer layer was first deposited on a Mo/glass substrate by RF sputtering method. Then, the preparation of AgGaTe₂ films was performed using a mixed powder source of Ag₂Te and Ga₂Te₃ [2]. In this study how the Ag₂Te buffer layer surface morphology was changed during the second CSS step.

The Ag₂Te layer was deposited on Mo/glass substrates by the RF sputtering method (the thickness was $0.1-0.3 \mu m$). Ag₂Te films were annealed in a tube furnace without depositing the material. We performed comparative experiments by changing the annealing temperature and time. The annealing temperature was varied from 400 °C to 600 °C with annealing time of 15 min to 75min. The surface morphological characterization was performed using an optical microscope. (VHX-5000, Keyence, Japan). The crystallographic properties were evaluated by a standard θ -2 θ measurements using XRD (Smart Lab, Rigaku, Japan). The layer exhibited a smooth surface before annealing, but this was changed after the annealing. Figure 1 shows optical microscopy images of Ag₂Te layers with varying the annealing temperature from 400 °C to

600 °C. The Ag₂Te layer exhibited small holes randomly distributed on the surface at 400 °C to 500 °C. The Ag₂Te layer surface exhibited a rugged and hollow film structure after annealing at 600 °C. Above 45 minutes of annealing, MoO₃ peaks were observed from XRD result. Dewetting process of Ag₂Te layer on Mo/glass substrate was observed for annealing at 400 °C ~500 °C. Dewetting process of these holes gradually became larger and the density of the holes with increasing the annealing temperature.

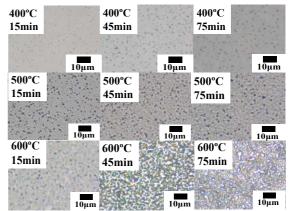


Figure 1 Optical microscopy images of Ag_2Te layers with varying the annealing temperature from 400°C to 600°C with annealing time of 15min to75min

References

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[2] A. Uruno, and M. Kobayashi, J. Electron. Mater. 45, 4692 (2016)